

从SPlasma Cleaner

CHARACTERISTICS

iSP 3LP500

 SIZE (mm) 760L x 810W x 810H

 WEIGHT (Kg) 125

 CHAMBER (mm) 550L x 460W x 610H

 SHELVE (mm) 400L x 300W

INTERNAL 300W 13.56MHz GENERATOR

 PROCESS CONTROL iPanel™

OPTIONS IPC, ADDITIONAL GAS CHANNELS

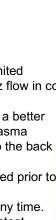
- Improved Electronic Control Unit: More robust connector vs dust
- Easy maintenance
- iPanel™ user interface with IP67 protective box and Tempered-Glass Screen Protector
- Compatible with all type of RF Generators
- 2 years' warranty (excluding travel expenses)
- Standard Electronic Rack easy to exchange
- Intuitive software
- CE Certificate



Yes Plasma UG

OTHER KEY POINTS

- Other key points
- The iSP Series controller allows unlimited process storage, direct reading of gaz flow in cc, on screen process notes ...
- Power is concentrated on shelves for a better uniformity and transfer of power to plasma
- No sputtering of the electrode buss to the back walls of the chamber
- Shelf configuration should be discussed prior to order
- System specification can change at any time. Consult DC sales representative for latest information



SAcide

SLaser

SPlasma

SMechanical





2018

FA Solutions and HighTech Equipment

SPlasma Cleaner

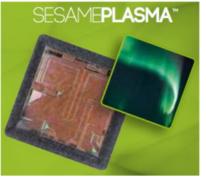
APPLICATIONS Cleaning

- Etching
- **Surface Activation**
- **Stripping Photoresist**
- Cleaning Hybrids
- **Desmearing Printed Circuit**
- R&D, Production



A GREEN WORLD WITH DC - LESS ACID - LESS CF4 - AND ALL FOR YOUR FUTURE IC PACKAGES





SPlasma Cleaner





New Power Plug







AP300/600 UG

New Optimized Power Bus



MAIN FEATURES

- Each of the iSP systems can be run in four plasma modes :
 - Down Stream : Samples are placed on the floating or neutral shelf surface for a gentle plasma effect
 - Direct: Samples are placed on the power or ground shelves for maximum effect
 - **Directional**: Samples requiring Anisotropic effect and maximum effect are placed on a special powered shelf
 - Special: Where parallel plate configurations do not serve as an optimum configuration special electrode configurations can be supplied
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narks mentioned or illustrated in this brochu









- iSP™ Standard Controller
- Easy Maintainability
- Standard Electronic Rack and iPanel easy to up-grade and exchange
- Up Grade with the last generation of controller iPanel™ instead of all the old electronics and PC-Windows.

(*) PATENTED (CNES/DC) LASER PLASMA TECHNOLOGY